

METHOD FOR PRODUCING SEMICONDUCTOR DEVICE AND APPARATUS FOR PRODUCING THE SAME

ABSTRACT

An apparatus 1 for producing a semiconductor device comprises a first reflow furnace 3 for heating a work 90 and a control unit 2, the first reflow furnace 3 comprises a first conveyor 31 being extended from an entrance to a heating zone 3b and a second conveyor 32 being extended from a cooling zone 3c to an exit, and the control unit 2 controls the first conveyor 31 and the second conveyor 32 to carry the work 90 to the heating zone 3b so as to melt solder, and to carry the work 90 to the cooling zone 3c so as to cure the solder and put the work 90 in an energizable-reworkable state.

Fig.1